

The invention relates to methods for measuring the resistance of metal microwires, in particular to measuring resistance under the simultaneous action of uniaxial deformation and transverse magnetic field, and can be used in the processes of studying the parameters of microwires in a magnetic field, namely in determining the change in resistance of metal microwires during deformation.

The method, according to the invention, consists in that the microwire is fixed on a bronze ring with two insulating plates, fixed on two opposite sides of the ring, previously deformed into an ellipsoidal shape, after which the microwire is subjected to deformation in the longitudinal direction by stretching it while compressing the ring using a microwire uniaxial deformation system, with the simultaneous application of a magnetic field transverse to the microwire, while measuring the resistance of the microwire depending on the magnitude of the transverse magnetic field at different values of deformation.

Claims: 1

Fig.: 1